PATENT
81848.0016.002

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of:

Chih-Chien Liu, et al.

Serial No: 09/991,196

Filed: November 20, 2001

For: High Density Plasma Chemical Vapor Deposition Process

Art Unit: 1796

Confirmation No. 3908

Examiner: Sergent, Rabon A.

I hereby certify that this correspondence is being transmitted via electronic filing to:
Mail Stop RCE
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450, on
03/18/08
Date of Deposit
Vivian Gut ierrez
Name
Vivian Gutierrez 03/18/2008
Signature Date

**PETITION FOR EXTENSION OF TIME**

Mail Stop RCE
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

In accordance with 37 C.F.R. 1.136, Applicants respectfully petition the Commissioner for a two-month extension of time extending to March 18, 2008, the period for response to the final Office Action dated October 18, 2007. Please charge the fee of $460.00 for this extension to Deposit Account No. 50-1314. The responsive paper(s) are attached.

Please charge any insufficiency or credit any overpayment to Deposit Account No. 50-1314. A copy of this petition is enclosed.

Respectfully submitted,

HOGAN & HARTSON L.L.P.

Date: March 18, 2008

By: William H. Wright /vmg
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